

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: ONO, Yuji et al.

Group Art Unit: 1746

Serial No.: 09/940,788

Examiner: Joseph L. Perrin

Filed: August 29, 2001

P.T.O. Confirmation No.: 4613

For: SINGLE WAFER TYPE SUBSTRATE CLEANING METHOD AND APPARATUS

AMENDMENT UNDER 37 CFR §1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

June 15, 2005

Sir:

In response to the Office Action dated April 1, 2005, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.